503117666 12/29/2014

## PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1 Stylesheet Version v1.2 EPAS ID: PAT3164274

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

#### **CONVEYING PARTY DATA**

Name	Execution Date
ADVANCED TECHNOLOGY MATERIALS, INC.	12/07/2014

### **RECEIVING PARTY DATA**

Name:	ENTEGRIS, INC.	
Street Address:	129 CONCORD ROAD	
City:	BILLERICA	
State/Country:	MASSACHUSETTS	
Postal Code:	01821	

## **PROPERTY NUMBERS Total: 6**

Property Type	Number	
Patent Number:	8785889	
Patent Number:	8399865	
Patent Number:	8237134	
PCT Number:	US2011026388	
Application Number:	61308428	
Application Number:	61390715	

### **CORRESPONDENCE DATA**

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ATTORNEY DOCKET NUMBER:	2771-942 FAMILY [7487]
NAME OF SUBMITTER:	STEVEN J. HULTQUIST
SIGNATURE:	/Steven J. Hultquist/
DATE SIGNED:	12/29/2014

**Total Attachments: 2** 

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PATENT |

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PATENT REEL: 034594 FRAME: 0976

## ASSIGNMENT

Advanced Technology Materials, Inc., a corporation of Delaware, United States of America, and the owner by assignment of all rights, title, ownership, and interests in and to the patents and patent applications identified in the attached Schedule A hereof ("Patent Assets"),

hereby transfers, sells, conveys, and assigns to

Entegris, Inc., a corporation of Delaware, United States of America, having offices at 129 Concord Road, Billerica, MA 01821 USA,

all rights, title, ownership, and interests in and to the Patent Assets, including the right to assert and enforce the Patent Assets against past infringement by third parties.

This Assignment is made in consideration of the undertaking of Entegris, Inc. to hereafter manage and administer the Patent Assets as fully and completely as Advanced Technology Materials, Inc. could have done in the absence of this Assignment, and in effectuation of the commitments and obligations of Advanced Technology Materials, Inc. pursuant to the acquisition of its parent company ATMI, Inc. by Entegris, Inc., as well as for other good and valuable consideration, the receipt and sufficiency of which is hereby acknowledged.

IN WITNESS WHEREOF, Advanced Technology Materials, Inc. has caused this Assignment to be executed by its duly authorized representative, who by his signature warrants and represents such authority, to be effective as of and from April 30, 2014.

Advanced Technology Materials, Inc.

Peter W. Walcott

Senior Vice President & Secretary

Date: 12/7/14

# Schedule A

U.S. Patent No.	Issue Date	US/PCT Appin. No.	Filing Date	Title
8,785,889	July 22, 2014	13/840,961	March 15, 2013	Method and
			·	Apparatus for
				Enhanced Lifetime
				and Performance
				of Ion Source in an
				Ion Implantation
***************************************				System
8,399,865	March 19, 2013	13/567,571	August 6, 2012	Method and
				Apparatus for
				Enhanced Lifetime
				and Performance
				of Ion Source in an
				Ion Implantation
			***************************************	System
8,237,134	August 7, 2012	13/401,527	February 21, 2012	Method and
				Apparatus for
				Enhanced Lifetime
				and Performance
				of Ion Source in an
				Ion Implantation
	***************************************		·····	System
		PCT/US2011/026388	February 26, 2011	Method and
				Apparatus for
				Enhanced Lifetime
				and Performance
				of Ion Source in an
				Ion Implantation
***************************************	***************************************			System
		61/308,428	February 26, 2010	Method and
				Apparatus for
				Enhanced Lifetime
				and Performance
				of Ion Source in an
				Ion Implantation
	ļ	22 m 2 ·· · · · ·		System
		61/390,715	October 7, 2010	Method and
				Apparatus for
				Enhanced Lifetime
				and Performance
				of Ion Source in an
				Ion Implantation
	1			System